

SEPARATE INJECTION OF REACTIVE SPECIES IN SELECTIVE FORMATION OF FILMS

BACKGROUND OF THE INVENTION

Field of the Invention

[0001] This application relates generally to semiconductor processing. More particularly, this application relates to the selective deposition of films and equipment configured for the same.

Description of the Related Art

[0002] As is well known, semiconductor processing is most commonly employed for the fabrication of integrated circuits, which entails particularly stringent quality demands, but such processing is also employed in a variety of other fields. For example, semiconductor processing techniques are often employed in the fabrication of flat panel displays using a wide variety of technologies and in the fabrication of microelectromechanical systems (MEMS).

[0003] A variety of methods are used in the semiconductor manufacturing industry to deposit materials onto surfaces. For example, one of the most widely used methods is chemical vapor deposition ("CVD"), in which atoms or molecules contained in a vapor deposit on a surface and build up to form a film. In some contexts, it is desirable to deposit selectively within semiconductor windows exposed among fields of different materials, such as field isolation oxide. For example, heterojunction bipolar transistors are often fabricated using selective deposition techniques that deposit epitaxial (single-crystal) semiconductor films only on active areas. Other transistor designs benefit from elevated source/drain structures, which provide additional silicon that can be consumed by the source/drain contact process without altering shallow junction device performance. Selective epitaxy on source/drain regions advantageously reduces the need for subsequent patterning and etch steps.

[0004] Generally speaking, selectivity takes advantage of differential nucleation and/or formation of different crystal morphology during deposition on disparate materials. Selective deposition can generally be explained by simultaneous

etching and deposition of the material being deposited. The precursor of choice will generally have a tendency to nucleate and grow more rapidly on one surface and less rapidly on another surface. For example, silane will generally nucleate on both silicon oxide and silicon, but there is a longer nucleation phase on silicon oxide. At the beginning of a nucleation stage, discontinuous films on oxide have a high exposed surface area relative to merged, continuous films on silicon. Similarly, the growth on the insulating regions can be amorphous or polycrystalline whereas growth on the semiconductor windows can be epitaxial. Accordingly, an etchant added to the process will have a greater effect upon the poorly nucleating film on the oxide as compared to the more rapidly nucleating film on the silicon. Similarly, an etchant can be more effective against amorphous or polycrystalline growth, whether from a prior deposition or during deposition, than against epitaxial growth. The relative selectivity of a process can thus be tuned by adjusting factors that affect the deposition rate, such as precursor flow rates, temperature, pressure, and factors that affect the rate of etching, such as e.g., etchant flow rate, temperature, pressure. Changes in each variable will generally have different effects upon etch rate and deposition rate. Typically, a selective deposition process is tuned to produce the highest deposition rate feasible on the window of interest while accomplishing no deposition in the field regions.

[0005] Known selective silicon deposition processes include reactants such as silane and hydrochloric acid with a hydrogen carrier gas. Co-owned and co-pending U.S. Patent Application No. 11/343,264, entitled "SELECTIVE DEPOSITION OF SILICON-CONTAINING FILMS," published as U.S. 2006/0234504 A1 on October 19, 2006, teaches processes that employ trisilane as a silicon source and chlorine gas as an etchant. These selective deposition processes show improved uniformity, purity, deposition speed and repeatability. However, strong exothermic reactions have been observed, potentially leading to premature reactant breakdown, damage to the gas intermixing tank, combustion, and substrate contamination. Other selective deposition chemistries are also subject to excessive reactivity. Accordingly, reaction apparatuses and selective deposition processes are desired that avoid such adverse effects while maintaining their efficacy for selective deposition.

SUMMARY OF THE INVENTION

[0006] Processes and equipment for selectively forming layers have now been discovered that minimize risk of violent reaction between precursors and etchant source chemicals. The described processes and equipment supply the reactive species to the reaction chamber separately rather than along common flow paths upstream of the reaction chamber. These processes and equipment avoid undesired heat formation and premature deposition, and reduce the risk of damage to expensive gas panel units. Separate flow paths to the chamber can avoid premature and harmful reactions for simultaneous precursor/etchant supply or for sequential supply of precursors and etchants.

[0007] One embodiment provides a method for selectively forming a semiconductor layer on a substrate in a reaction space, where the substrate includes a first surface and a second surface. The method includes separately introducing a precursor for semiconductor deposition and a vapor etchant through separate flow paths into the reaction space. The substrate is exposed to the precursor and to the vapor etchant. The method further includes selectively forming the semiconductor layer on the first surface at a greater mean rate than on the second surface.

[0008] Another embodiment provides an apparatus for selectively forming a semiconductor film on a substrate. The apparatus includes a chemical vapor deposition (CVD) reactor that includes a reaction space. A substrate support is positioned within the reaction space and the substrate support is sized and shaped to receive a silicon wafer. A first inlet set of one or more inlets is in fluid communication with the reaction space and a second inlet set of one or more inlets is in fluid communication with the reaction space. A first gas source is configured to supply a precursor for semiconductor deposition to the first inlet set. A second gas source is configured to supply an etchant to the second inlet set. The inlet sets and sources define separate flow paths for the precursor and the etchant to a mixing space within the reaction space.

[0009] Another embodiment provides an apparatus including a chemical vapor deposition (CVD) reactor that includes a reaction space. A substrate support is positioned within the reaction space. A first inlet set of one or more inlets is in fluid communication with the reaction space, wherein the first inlet set comprises a manifold configured to spread a precursor for semiconductor deposition across a width of the reaction space via a plurality of inlets. A second inlet set of one or more inlets is in fluid communication with the reaction space. A first gas source is configured to supply the precursor to the first

inlet set and a second gas source is configured to supply an etchant to the second inlet set. The inlet sets and sources define separate flow paths for the precursor and the etchant to a mixing space within the reaction space. These and other embodiments are described in greater detail below.

BRIEF DESCRIPTION OF THE DRAWINGS

[0010] These and other aspects of the invention will be readily apparent from the following description and from the appended drawings (not to scale), which are meant to illustrate and not to limit the invention, and in which:

[0011] **FIG. 1** shows a known apparatus for chemical vapor deposition (CVD) on a substrate.

[0012] **FIG. 2** is a schematic diagram of a CVD system in accordance with an embodiment.

[0013] **FIG. 3** is a cross-sectional side view of a CVD system in accordance with an embodiment.

[0014] **FIG. 4** is a detailed view of the CVD system shown in **FIG. 3**.

[0015] **FIG. 5** is a cross-sectional front view of a CVD system in accordance with an embodiment.

DETAILED DESCRIPTION OF THE EMBODIMENTS

[0016] In many selective deposition processes, Si-containing layers are selectively formed over single crystal semiconductor materials while minimizing and more preferably avoiding deposition over adjacent dielectrics. Examples of dielectric materials include silicon dioxide (including low dielectric constant forms such as carbon-doped or fluorine-doped), silicon nitride, metal oxide and metal silicate. More generally, patterned or mixed substrates have two or more different types of surfaces. There are various ways that the surfaces of a mixed substrate can be different from each other. For example, the surfaces can have different material compositions, different crystal morphologies and/or different electrical properties.

[0017] Even if the materials are made from the same composition, surfaces can be different if the morphologies, i.e., the crystallinity of the surfaces, are different. The processes described herein are useful for depositing Si-containing films on a variety of substrates, but are particularly useful for mixed substrates having mixed surface

morphologies. A mixed substrate with a mixed surface morphology is a substrate that includes a first surface having a first surface crystal structure and a second, different surface crystal structure. Amorphous, polycrystalline and single crystal are examples of different morphologies.

[0018] Epitaxial deposition refers to the deposition of a crystalline semiconductor material onto a crystalline substrate in such a way that the deposited layer adopts or follows the lattice constant of the substrate. Epitaxial deposition may be homoepitaxial or heteroepitaxial. Homoepitaxial deposition occurs when the deposited layer is formed of the same material as that of the substrate, such as epitaxially depositing a layer of silicon on a single-crystal silicon substrate. Heteroepitaxial deposition occurs when the composition of the deposited layer differs from that of the substrate, such as when epitaxially depositing germanium or silicon germanium on a single-crystal silicon substrate.

[0019] Epitaxial films are characterized by a crystal structure and orientation that is identical to the substrate upon which they are grown. Typically, the substrate is a single crystal, such that the epitaxial film is also a single crystal. The atoms in these materials are arranged in a consistent lattice-like structure that persists over relatively long distances on an atomic scale. By contrast, amorphous morphology is a non-crystalline structure having a low degree of order because the atoms lack a definite repetitive arrangement. Other morphologies include microcrystalline and mixtures of amorphous and crystalline material. As used herein, a "single-crystal" structure is implied by epitaxial deposition and is used to describe a predominantly large crystal structure that may have a tolerable number of faults therein, as is commonly employed for transistor fabrication. The skilled artisan will appreciate that crystallinity of a layer generally falls along a continuum from amorphous to polycrystalline to single-crystal; the skilled artisan can readily determine when a crystal structure can be considered single-crystal or epitaxial, despite low density faults. The skilled artisan will understand that methods described herein for depositing Si-containing films onto mixed or patterned substrates having two types of surfaces may also be applied to mixed substrates having three or more different types of surfaces.

[0020] FIG. 1 illustrates a conventional system for chemical vapor deposition (CVD) on a substrate 80. "Substrate," as that term is used herein, refers either to the workpiece upon which deposition is desired, or the surface exposed to reactant gases. For

example, the substrate **80** may be a single crystal silicon wafer, or may be a semiconductor-on-insulator (SOI) substrate, or may be an epitaxial Si, SiGe or III-V material previously formed upon such wafers. Wafers include substantially flat substrates, such as those having diameters of 200 mm, 300 mm, and 450 mm. Substrates are not limited to wafers, but also include glass, plastic, or any other substrate employed in semiconductor processing. Gases, including vapors from a first reactant source **10** and a second reactant source **20**, are supplied to a gas panel **100**. Inert gases from an inert gas source **40** are typically also added to aid in the chemical vapor deposition process.

[0021] It is conventional to mix the reactive gases **10**, **20** upstream of the reaction chamber **300** because a well-mixed, homogenous mixture or feed gas **30** with a uniform concentration of reactants can facilitate uniform deposition on the substrate **80** once the feed gas **30** reaches the reaction chamber **300**. Thus, for a single-pass, laminar, horizontal flow single wafer reactor, it is conventional to intermix the reactive gases from the reactant sources **10**, **20** at the gas panel **100** to promote uniform deposition on the substrate **80** in the reaction chamber **300**. Once the gases from the sources **10**, **20**, **40** have been intermixed in the gas panel **100**, the feed gas **30** is delivered to an inlet distribution manifold **200**. The manifold **200** serves to distribute the flow of the feed gas **30** across the width of the reaction chamber **300**. The manifold **200** may be configured to distribute flow in such a way to enhance uniformity of the semiconductor deposition on the substrate **80** in the reaction chamber **300**. Typically, the delivery of the feed gas **30** from the gas panel **100** to the inlet distribution manifold **200** is accomplished through pipes or tubes with cross-sectional areas that are substantially smaller than that of the gas panel **100**. Such pipes or tubes may include valves to regulate the flow of the feed gas **30**. Further, within the manifold **200**, the feed gas **30** may pass through other piping that restricts the flow of the feed gas **30** into the reaction chamber **300**. Thus, the feed gas **30** will typically pass through one or several bottlenecks or flow restrictions within and downstream of the gas panel **100**, after the gases from the reactant sources **10**, **20** have been intermixed.

[0022] Selective formation processes using a precursor for semiconductor deposition from the first reactant source **10** and an etchant from the second reactant source **20** show excellent selectivity and deposition speed. Generally, selective deposition processes result in net deposition rates over semiconductor areas being greater than 5

times, and preferably greater than 10 times, rates of deposition over insulators and windows. Fully selective processes result in no net deposition over insulators or metals. Net deposition rates are calculated over the entire process, whether simultaneously or sequentially providing precursors and etchants. However, some of these processes have shown strong exothermic reactions when the precursor for semiconductor deposition and etchant gas intermix. Precursors for CVD of semiconductors can be selected from the group of silicon precursors, germanium precursors and carbon precursors. Silicon precursors may include trisilane (Si_3H_8), dichlorosilane (H_2SiCl_2 , "DCS"), disilane (Si_2H_6), partially chlorinated disilane, methyl silane, silane (SiH_4) or 2,2-dichlorotrisilane. Germanium precursors include germane, digermane and trigermane. Carbon precursors include silylalkanes such as monosilylmethane, disilylmethane, trisilylmethane and tetrasilylmethane, and/or alkylsilanes such as monomethyl silane (MMS), and dimethyl silane. In some embodiments, a carbon precursor comprises $\text{H}_3\text{Si-CH}_2\text{-SiH}_2\text{-CH}_3$ (1,3-disilabutane) or $\text{CCl}_2(\text{SiH}_3)_2$ (2,2-dichlorodisilylmethane). Etchant sources include chlorine gas (Cl_2).

[0023] Taking trisilane and chlorine gas as an example, it is believed that at high enough partial pressures, Cl_2 reacts with Si to produce silicon tetrachloride (SiCl_4) in an exothermic reaction. The highly exothermic hypergolic reaction of Cl_2 with Si_3H_8 can lead to combustion of the silicon precursor. The reaction can occur upstream the reaction chamber 300 and therefore lead to premature silicon deposition, which can also lead to subsequent spalling or aerosol particle formation and contamination. In addition, the powerful exothermic reactions can damage the equipment at the point of interaction, such as expensive gas panel units 100. Similar issues can arise with other combinations of semiconductor precursors and etchant gases. Without being limited by theory, it is believed that interaction among the reactant gases in a limited volume and/or passing the reactant gases along common or shared flow paths through flow restrictions prior to entry into the reaction chamber 300 may contribute to these problems. Interaction between highly reactive precursors and etchants under the high pressures caused by these restrictions in a very confined flow path might cause the highly energetic and even explosive reactions that have been observed. Damage is greater in confined passages, and may exacerbate reactivity by inhibiting heat dissipation, relative to wider, more voluminous spaces. Note that such interaction can occur within these tight confines whether the reactants are supplied simultaneously or sequentially. In sequential supply,

residual reactants from a first pulse inevitably remain within the shared flow path when the next pulsed is supplied, which can then react in the shared flow path upstream of the chamber.

[0024] Embodiments taught herein avoid undesired effects of highly reactive combinations of a semiconductor precursor and an etchant species in selective formation processes by separately injecting the reactive species into the reaction chamber 300. Particularly volatile combinations of precursor and etchant produce reactions that are at least as exothermic as the reaction of DCS + Cl₂. Several highly reactive combinations include without limitation pentasilane + Cl₂; tetrasilane + Cl₂; trisilane + Cl₂; disilane + Cl₂; and partially chlorinated disilane + Cl₂. FIG. 6 compares the exothermicity of several exemplary combinations of silicon precursors and etchants. The table below compares exothermicity, in terms of approximate enthalpy values, for certain silicon precursors when combined with Cl₂.

Silicon Precursor	Enthalpy at 0°C (kcal/mol)	Enthalpy at 550°C (kcal/mol)
Trisilane	-450	-550
Silane	-500	-500
Disilane	-460	-460
Monochlorodisilane	-400	-380
Dichlorodisilane	-340	-320
Trichlorodisilane	-270	-250
Dichlorosilane	-270	-250
Tetrachlorodisilane	-220	-200
Pentachlorodisilane	-150	-130

[0025] While much of the description herein focuses on the exemplary combination of trisilane + Cl₂, the skilled artisan will readily appreciate from the disclosure herein that the described equipment will also benefit process recipes employing other highly reactive combinations, particularly those more exothermic than DCS + Cl₂, at the reaction temperature (e.g., more exothermic than -270 kcal/mol at 0°C or -250 kcal/mol at 550°C).

[0026] Without limiting the invention by theory, it is believed that embodiments of the present invention minimize the risk of premature reactant breakdown, combustion, damage to equipment and substrate contamination by providing separate flow paths for precursors and etchants, thereby avoiding their interaction under high pressure in a limited volume at the gas panel 100 or between the gas panel 100 and the reaction chamber 300. Moreover, the reactivity of the gases can be further minimized by supplying an increased amount of carrier gas and thereby reducing the partial pressure of the reactants, shortening the residence time of the gases, increasing the velocity of the gases and/or improving the heat capacity of the gases. Because the gases avoid interaction in high pressure regions that could trigger or exacerbate upstream reactions, intermediate reactive species (e.g., SiHCl, SiH₂ and Si₂H₄ for Si₃H₈ + Cl₂ reactants) can reach the substrate 80 rather than having the reaction completed prematurely. Additionally, the risk of damaging the expensive equipment is reduced.

[0027] A schematic diagram of a selective deposition system in accordance with an embodiment of the present invention is shown in FIG. 2. In an embodiment, the CVD reaction chamber 300 can be a single wafer reactor, particularly a horizontal gas flow CVD chamber. In some embodiments, the reaction chamber 300 is a cold wall, radiantly heated, single-wafer, single pass, laminar horizontal gas flow reactor. Suitable reactors of this type are commercially available, including the Epsilon™ series of single-wafer reactors commercially available from ASM America, Inc. of Phoenix, Arizona. The reaction chamber 300 of the illustrated embodiment (see FIG. 3) includes a rotating substrate, and permits low process gas residence times. CVD may be conducted by introducing plasma products to the chamber, either in situ or downstream of a remote plasma generator. Alternatively, thermal CVD can be used.

[0028] As illustrated in FIG. 2, a first reactant source 10 and a second reactant source 20 are in fluid communication with a gas panel 100. The first and second reactant sources 10, 20 are chosen to promote selective formation of semiconductor films on the substrate. As explained above, selective deposition means that a film, such as silicon, is deposited on a first portion of the surface of the substrate at a greater mean rate than on a second portion of the same surface. In some selective deposition embodiments, the rate of semiconductor deposition on the second portion may be approximately the same rate at which silicon is etched away, resulting in an effective deposition rate of zero on the second portion. Cyclical deposition and etching can have the same effect.

[0029] In an embodiment, the first reactant source **10** contains a silicon precursor, such as a precursor selected from the group consisting of pentasilane, tetrasilane, trisilane, DCS, disilane, partially chlorinated disilane, methyl silane and silane. In other embodiments, the first reactant source **10** contains a carbon precursor. In other embodiments, the first reactant source **10** contains a germanium precursor. The first reactant source **10** can represent multiple reactant vessels, such as for deposition of SiGe, Si:C or SiGe:C. The second reactant source **20** can contain a halogen-containing etchant to provide selectivity to the deposition process. Embodiments can employ a chlorine-containing species, such as diatomic chlorine gas (Cl_2), in the second reactant source **20**. Employing diatomic chlorine as an etchant can provide superior etch capability even at low temperatures in the range of 400°C and 600°C, but can be highly reactive in combination with precursors for semiconductor deposition. As noted above, processes taught herein provide particular advantages when the combination of the first reactant source **10** and the second reactant source **20** is a highly reactive combination that produces exothermic reactions.

[0030] An inert gas source **40** may also communicate with a gas panel **100** as a purge gas and/or carrier gas for either the first reactant source **10** or the second reactant source **20**. Among other roles, the inert gas source **40** can provide backpressure for the reactants at their inlets to the chamber **300**, thus preventing gas from the first reactant source **10** from diffusing into a second inlet manifold **220** and vice versa, whether for simultaneous or sequential supply of precursors and etchants. The inert gas source **40** can also remove heat due to its heat capacity, thereby lowering the temperature of the reactants. Further, the inert gas source **40** can dilute gas from the first and second reactant sources **10**, **20** (i.e., reduce the concentration of the reactants), thereby slowing the reaction and aiding stable, slow decomposition of the precursors where desired. This, in turn, yields favorable precursor utilization and high growth rates for the film, as well as a lower temperature in the reaction chamber **300**. In order to minimize exothermic reactions, in some embodiments the inert gas source **40** includes helium (He), argon (Ar), nitrogen (N_2), xenon (Xe), krypton (Kr), neon (Ne), hydrogen chloride (HCl) or other gases that are nonreactive under deposition conditions. The carrier gas may further include inhibitors such as those disclosed in co-owned and co-pending U.S. Patent Application No. 11/925,518, entitled "INHIBITORS FOR SELECTIVE DEPOSITION OF SILICON CONTAINING FILMS," which is hereby incorporated by reference for its

description of suitable inhibitor agents for decelerating reactions between silicon precursors and chlorine-containing ethcants. Examples include propylene, butadiene, benzene, naphthalene, phenanthrene, anthracene, cycloheptatrienecation, cycloheptatrien, furan, pyridine, pyrrole and thiophene. Because of the ability of the inert gas source 40 to dilute and lower the temperature of the first and second reactant sources 10, 20 and thus inhibit the reaction, relatively higher flow rates of gas from the inert gas source 40 may be supplied for relatively more reactive combinations of the first and second reactant sources 10, 20. For example, in embodiments employing trisilane and chlorine gas, which is a very highly reactive combination, the gas from inert gas source 40 may have a flow rate between about 10 and 40 slm.

[0031] The gas panel 100 may include valves, mass flow controllers (MFCs), and other control elements that allow the operator to balance various parameters to optimize deposition in the reaction chamber 300. Such parameters include, but are not limited to, flow rates, temperatures, and total pressures for vapors from the inert gas source 40, first reactant source 10, and second reactant source 20, as well as molar ratio between the precursor for semiconductor deposition of the first reactant source 10 and the chlorine-containing species of the second reactant source 20. In embodiments in which trisilane is employed as the first reactant source 10 simultaneously with the second reactant source 20, the molar ratio between the trisilane and the chlorine-containing species may be between about 1:3 and 1:12, particularly between about 1:5 and 1:10. To moderate reactivity, flow rates for trisilane can be less than about 100 milligrams per minute, particularly less than about 50 milligrams per minute, more particularly less than about 25 milligrams per minute.

[0032] Significantly, while the inert gas source 40 may be combined with either the first reactant source 10 or the second reactant source 20 or both, embodiments prevent interaction of the vapor phase reactants from the first reactant source 10 and the second reactant source 20 in the gas panel 100. Instead, the flow paths of gas from the first reactant source 10 and gas from the second reactant source 20 intersect for the first time only at a mixing point or space within the reaction chamber 300. Suitable gas panels are commercially available, such as the E2000™, E2500™, E3000™, E3200™ and E3220™ from ASM America, Inc. of Phoenix, Arizona.

[0033] Referring still to **FIG. 2**, gases or vapors from the reactant sources **10**, **20** communicate with the reaction chamber by way of an inlet flange **205**. In particular, vapor from the gas panel **100**, from the first reactant source **10** flows to a first inlet manifold **210** of the inlet flange **205**, while vapor from the second reactant source **20** flows separately to a second inlet manifold **220** of the inlet flange **205**. The inlet manifolds **210**, **220** are configured to distribute gas across the width of a reaction space **340** defined in part by the reaction chamber **300**. An exhaust flange **360** on a downstream end of the reaction chamber **300** comprises an exhaust outlet **361**, which is configured to evacuate excess reactant vapors and reaction by-product from the reaction space **340**. This process may be effectuated by means of a pump **362** communicating with the exhaust outlet **361**.

[0034] **FIG. 3** is a schematic cross-section illustrating the reaction space **340**. The reaction space **340**, as described herein, includes the space defined by the quartz walls of the reaction chamber **300** in addition to an upstream wafer insertion opening of the inlet flange **205**, through which wafers are loaded and unloaded. The precursor and etchant flow paths are kept separate through the first and second inlet manifolds **210**, **220** and intersect for the first time at a mixing space **342** within the wafer insertion opening **341**. From the mixing point **342**, the precursor and etchant follow a shared or common flow path over a substrate support **350**, which is sized and shaped to support the substrate **80**. Excess reactants and by-products continue along the laminar, horizontal, common flow path to the exhaust flange **360**.

[0035] As shown in **FIGS. 3-5**, the first or upper inlet manifold **210** may include several injectors **212** that control relative flow into a reaction space **340** within the reaction chamber **300**.

[0036] Specifically, gas from the first reactant source **10** enters a channel **211** (see **FIG. 5**) in communication with each of the injectors **212**. Each of the injectors **212** controls a flow path from the channel **211** through an associated entrance tube **213**. Each entrance tube **213** leads into a horizontal channel **214**, which traverses a portion of the width of a reaction space **340**. From the channel **214**, gases flow into the reaction space **340** via slits **216**. The slit **216** has a smaller cross-sectional area, transverse to the gas flow path, than the channel **214** and is therefore a bottleneck or flow constriction on gases from the first reactant source **10**, aiding in spreading the gases across the portion of the

width of the reaction space 340 that the slit 216 traverses. FIGS. 3-5 illustrate one embodiment of the first inlet manifold 210, but other configurations can alternatively be employed to distribute gas across the width of the reaction chamber 300. For example, gas from the first reactant source 10 may flow into the reaction space 340 directly from a single channel or from a single slit that traverses all or a substantial portion of the width of the reaction space 340, rather than from multiple slits 216 as shown. Thus, the first inlet manifold 210 can define multiple inlets to the reaction space 340, as shown, or a single inlet.

[0037] With respect to the second or lower inlet manifold 220, gas from the second reactant source 20 supplied by the supply line 222 flows into a lower horizontal channel 224, which traverses all or a portion of the width of the reaction space 340 in order to more evenly distribute gas. From the lower channel 224, gases flow into the reaction space 340 via a plurality of lower entrance tubes 226. As shown in FIGS. 4-5, the plurality of lower entrance tubes 226 comprise discrete passages distributed across the width of the reaction space 340. In the illustrated embodiment, the lower entrance tubes 226 are positioned on an opposite wall, across from and between the slits 216 of the first inlet manifold 210 in order to facilitate uniform mixing of the gases upon entry into the reaction space 340 for operation of simultaneous supply modes of operation. Even for sequential supply modes, the illustrated arrangement of alternation of the upper and lower inlets, represented by the slits 216 and lower entrance tubes, respectively, can aid spreading the reactants supplied therethrough by mixing inert gas from one of the inlet sets when reactant flows from the other of the inlet sets. In an alternative embodiment not shown in the figures, vapor from the second reactant source can enter the reaction space 340 via a single slit or a plurality of slits with a width that traverses all or a substantial portion of the width of the reaction space 340 such that the inlet(s) of the second inlet manifold 220 can resemble the inlets or slits 216 of the first inlet manifold 210. Gas from the supply line 222 is provided with sufficient backpressure to prevent gas from the first reactant source 10 from diffusing into the inlets 226 in either simultaneous or sequential supply modes of operation.

[0038] As such, gas from the first reactant source 10 has the potential to interact with gas from the second reactant source 20 at a mixing space 342 in the reaction

space **340**. The mixing space **342** thus represents the first intersection between the flow paths of reactants from the first reactant source **10** and the second reactant source **20**.

[0039] In some modes of operation, gas from the first reactant source **10** and gas from the second reactant source **20** are introduced sequentially into the reaction space **340** such that the reactants from the reactant sources **10**, **20** are not intended to mix during processing. The illustrated separate flow paths still reduces the risk of explosive interaction between reactants for such sequential modes of operation. Because the illustrated inlet flange **205** keeps the flow paths for the reactants separate until they intersect at the mixing space **342**, there is no danger that residual reactant from one pulse will interact with a subsequent pulse of the other reactant within the confines of the gas panel **100** (FIG. 2) or the inlet manifolds **210**, **220**. The disclosure of co-owned and copending U.S. Patent Application Publication No. 2007/0287272, published December 13, 2007, attorney docket no. ASMEX.583A, is incorporated by reference herein for the purposes of describing exemplary processes in which selective formation of semiconductor films is accomplished by supplying deposition precursors and etchants sequentially, rather than simultaneously. The sequential and preferably cyclical process of the '463 patent application provides for blanket deposition over insulating and single-crystal silicon surfaces of a patterned or mixed substrate, followed by selective etching of non-epitaxial material. The blanket deposition is conducted in the absence of etchant, or with low enough levels of etchant as to result in significant net deposition on all surfaces. Epitaxial semiconductor material is left on single crystal semiconductor windows of the patterned substrate, while non-epitaxial material is left on other surfaces, such as metals on insulators. Non-epitaxial (e.g., amorphous or poly) semiconductor material is more susceptible to etching, and the subsequent etchant pulse is timed to remove all non-epitaxial material from the deposition while leaving at least some of the epitaxial material from the deposition.

[0040] In other modes of operation, the gases are introduced simultaneously into the reaction space **340** and actually mix and interact during selective deposition. As the precursors and etchants mix within the reaction space, under lower pressures and in a larger volume than the upstream gas panel **100** (FIG. 2) and inlet manifolds **210**, **220**, there is less risk of damage to equipment from violent reactions. Preferably conditions are selected to maintain 100% selectivity, for example, zero net deposition over insulating surfaces and some net epitaxial deposition over single crystal semiconductor windows.

[0041] Referring back to **FIG. 2**, the above-described simultaneous and sequential modes of operation can be implemented by instructions or programming of a controller **250**. The controller **250**, which can include a general purpose or special purpose computer, communicates with devices on the gas panel **100**, such as valves and mass flow controllers, as well as flow control devices at other locations. For example, one or more of the sources **10**, **20** can have control valves and heaters in communication with the controller **250**. The controller **250** also adjusts other devices that affect processing parameters, such as a temperature control system, which in turn receives input from temperature sensors and adjusts power to radiant heaters outside the chamber **300**, and the vacuum pump **362**. The controller **250** is thus programmed to implement process recipes, such as the simultaneous or the sequential selective epitaxial formation processes described above.

[0042] The embodiment shown in **FIGS. 3-5** provides first and second inlet manifolds **210**, **220** injecting gases from above and below into the reaction space **340**. Reactants from the reactant sources **10**, **20** thus flow from opposite walls or opposite directions into the reaction space **340**. The skilled artisan will appreciate that some of the advantages of the equipment and processes taught herein will be obtained with other geometric configurations.

[0043] As illustrated in **FIG. 3**, the substrate **80** is located within the reaction space **340**, and the reactant gases may flow freely without being subjected to any flow restrictions from the mixing space **342** to the substrate **80**. The width of the portion of the reaction space **340** containing the mixing space **342** can be at least as wide as the substrate **80**, and in the illustrated embodiment the mixing space **342** is within the wafer insertion opening **341**, which is sized and shaped to pass a substrate **80** through it for loading and unloading. The lack of flow restrictions means that the reactant gases are not subjected to increased pressure at the mixing point, where interaction is possible. Accordingly, premature semiconductor deposition or other unwanted e.g., explosive, reactions can be avoided. The pressure differential may be substantially zero between the mixing space **342** and the substrate **80**. In some embodiments, however, the pressure differential may be negative, which is to say the pressure may decrease between the mixing space **342** and the substrate **80**. In some embodiments, temperature in the reaction

space 340 is below about 750°C, and particularly between about 500°C and about 600°C. Total pressure in the reaction space 340 may be between 1 Torr and 200 Torr.

Example 1: Sequential Flow of Trisilane and Cl₂

[0044] In one process according to embodiments of the invention, a blanket (non-selective) deposition was carried out using trisilane, along with methyl silane as a carbon source and phosphine as a dopant. This process was carried out using the equipment described above, with separated inlets into the reaction space. The temperature in the reaction space during the deposition was approximately 550°C, and the pressure was approximately 100 Torr. Next, a purge was performed for five seconds and the pressure was reduced to approximately 10 Torr. The etch phase was then carried out using Cl₂. This process was found to avoid the problem of premature silicon deposition. The flow rates of gases in this process can be optimized to balance speed and uniformity. As noted above, sequential blanket deposition processes can be performed over a patterned substrate having insulating and single-crystal silicon surfaces. During the blanket deposition, epitaxial semiconductor material is left on single-crystal semiconductor windows of the patterned substrate, while nonepitaxial material is left on other surfaces, such as insulators. The subsequent etch phase can then remove the nonepitaxial material. Etch rate selectivity, defined as the etch rate of amorphous material divided by the etch rate of the single-crystal, was found to be greater than 7.

Example 2: Simultaneous Flow of DCS and Cl₂

[0045] In another process according to embodiments of the invention, the silicon precursor DCS was introduced simultaneously with the etchant Cl₂ along with methyl silane as a carbon source and phosphine as a dopant. This process was carried out using the equipment described above, with separated inlets into the reaction space. Reaction space temperature was between about 550°C and about 600°C, and pressure in the reaction space was atmospheric. The flow rate for DCS was about 500 sccm. The flow rate for Cl₂ was between about 3 sccm and about 10 sccm. This process was found to avoid the problem of premature silicon deposition.

Example 3: Simultaneous Flow of Trisilane and Cl₂

[0046] In another process according to embodiments of the invention, the silicon precursor trisilane was introduced simultaneously with the etchant Cl₂. This process was carried out using the equipment described above, with separated inlets into the reaction space. Reaction space temperature was between about 525°C and about 575°C, and pressure in the reaction space was between about 4 Torr and about 32 Torr. Trisilane was introduced at a flow rate of about 50 mg/min for about 10 minutes, while about 200 sccm Cl₂ and about 100 sccm of 1% phosphine was simultaneously introduced. This process was found to avoid the problem of premature silicon deposition, and selectivity of the deposition was found to be acceptable.

[0047] The foregoing embodiments provide methods and equipment for separately providing precursors for semiconductor deposition and etchants that provide selectivity. The first intersection, or mixing space, for these two reactants is within the relatively spacious reaction space, rather than upstream manifolds and gas panels. By avoiding interaction within the tight confines of portion flow paths upstream of the reaction space, potentially harmful reactions are avoided or such reactions take place within the reaction space where reactions are not confined to a small volume, pressures can be kept lower, and less damage is incurred. Advantages are obtained whether the precursors and etchants for selective film formation are supplied simultaneously or in sequential steps.

[0048] Although this invention has been disclosed in the context of certain embodiments and examples, it will be understood by those skilled in the art that the present invention extends beyond the specifically disclosed embodiments to other alternative embodiments and/or uses of the invention and obvious modifications thereof. Thus, it is intended that the scope of the present invention herein disclosed should not be limited by the particular disclosed embodiments described above, but should be determined only by a fair reading of the claims that follow.

I CLAIM:

1. An apparatus for selectively forming a semiconductor film on a substrate, the apparatus comprising:

a chemical vapor deposition (CVD) reactor comprising a reaction space;

a substrate support within the reaction space, wherein the substrate support is sized and shaped to receive a substrate;

a first inlet set of one or more inlets in fluid communication with the reaction space;

a second inlet set of one or more inlets in fluid communication with the reaction space;

a first gas source configured to supply a precursor for semiconductor deposition to the first inlet set; and

a second gas source configured to supply an etchant to the second inlet set, wherein the inlet sets and sources define separate flow paths for the precursor and the etchant to a mixing space within the reaction space, and wherein the flow paths and reaction space are positioned such that the etchant and precursor are uniformly mixable and have a common flow path from the mixing space to the substrate on the substrate support for selectively forming a semiconductor film on the substrate.

2. The apparatus of Claim 1, wherein there are no restrictions to fluid flow between the mixing space and the substrate support.

3. The apparatus of Claim 1, wherein the mixing space has a width sufficient to pass the substrate therethrough.

4. The apparatus of Claim 1, wherein the CVD reactor comprises a single wafer, horizontal flow chamber.

5. The apparatus of Claim 4, wherein the first and second inlet sets are formed in an inlet flange adjacent the chamber, wherein the reaction space includes the mixing space defined by the inlet flange and an inner space defined by the chamber.

6. The apparatus of Claim 1, wherein the first and second inlet sets are disposed on different walls of the mixing space.

7. The apparatus of Claim 6, wherein the first and second inlet sets are disposed on opposing walls of the mixing space.

8. The apparatus of Claim 6, wherein the first and second inlet sets are disposed at an inlet end of the chamber, the substrate support being positioned between the inlet end and an exhaust end of the chamber.

9. The apparatus of Claim 8, wherein the first and second inlet sets are disposed above and below the mixing space, respectively.

10. The apparatus of Claim 1, wherein the precursor includes trisilane (Si_3H_8).

11. The apparatus of Claim 1, wherein the etchant includes diatomic chlorine (Cl_2).

12. The apparatus of Claim 1, wherein a carrier gas is supplied to the second inlet set, the carrier gas comprising at least one non-hydrogen containing inert gas.

13. The apparatus of Claim 1, wherein the CVD reactor comprises radiant heaters configured to heat a substrate positioned on the substrate support.

14. The apparatus of Claim 1, wherein the mixing space is defined within a substrate insertion opening adjacent to a gate valve that is located at an end of the reaction space.

15. The apparatus of Claim 1, further comprising a controller programmed to alternately and sequentially supply the precursor and the etchant to the first and second inlet sets, respectively.

16. The apparatus of Claim 1, further comprising a controller programmed to simultaneously supply the precursor and the etchant to the first and second inlet sets, respectively.

17. An apparatus comprising:
a chemical vapor deposition (CVD) reactor comprising a reaction space;
a substrate support within the reaction space;

a first inlet set of one or more inlets in fluid communication with the reaction space, wherein the first inlet set comprises a manifold configured to spread a precursor for semiconductor deposition across a width of the reaction space via a plurality of inlets;

a second inlet set of one or more inlets in fluid communication with the reaction space;

a first gas source configured to supply the precursor to the first inlet set; and

a second gas source configured to supply an etchant to the second inlet set, wherein the inlet sets and sources define separate flow paths for the precursor and the etchant to a mixing space within the reaction space, and wherein the flow paths and reaction space are positioned such that the etchant and precursor are uniformly mixable and have a common flow path from the mixing space to a substrate on the substrate support for selectively forming a semiconductor film on the substrate.

18. The apparatus of Claim 17, wherein the second inlet set comprises a manifold configured to spread the etchant across a width of the reaction space via a plurality of slits.